

ABSTRACT OF THE DISCLOSURE

A defect inspection system according to the present invention comprises image acquiring section for acquiring a two-dimensional image of a subject which is a processing target in a manufacturing process, defect  
5 extracting section for extracting a defect by a defect extraction algorithm using a predetermined parameter for an image acquired by the image acquiring section, displaying section for displaying an image of a defect  
10 of the subject extracted by the defect extracting section, parameter adjusting section for adjusting the parameter in accordance with a defect extraction degree for the subject, and quality judging section for  
judging the quality of the subject based on a defect  
15 information extracted by the defect extracting section.